

The precise solution for mass spectrometry. Modular design. Powerful software. Wide range of applications.



The precise solution for mass spectrometry.

The combination of high sensitivity, maximum stability and intelligent operation make the PrismaPlus the perfect solution for mass spectrometry.

Its modular design offers you a variety of application options in industrial and analytical environments, in research & development, in leak detection and semiconductor production, as well as in coating technology.

The PrismaPlus is the ideal solution for applications ranging from quality assurance and residual gas analysis right through to complex, quantitative tasks.

The Quadera[®] software is a further plus. In addition to being especially easy to operate, it also serves as an easy-to-read platform for transferring all measured data.

Together with a wide selection of interfaces, such as digital and analog inputs and outputs or Ethernet, integration into your system is easily achieved.

Our product and service professionals around the world stand ready to provide you with application assistance on the implementation of the PrismaPlus. Many decades of customer and application-specific experience make Pfeiffer Vacuum your ideal partner.

The added plus for gas analysis!



Accelerator



Coating



Research & Development



Advantages at a glance

- Modular design offers optimum adaptability
- Compact size yet high performance
- A variety of interfaces make for simple systems integration
- Networkable through Ethernet
- High measurement speed, stability and resolution
- Interchangeability of analyzers and electronics

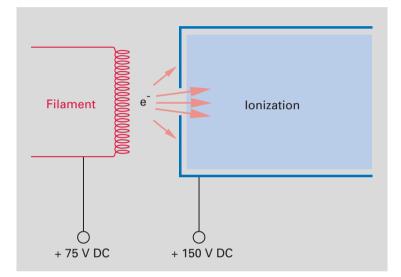
- Two filaments mean maximum up-time
- Lowest detectable partial pressure 1 · 10⁻¹⁴ hPa (mbar)
- Connectable Pfeiffer Vacuum total pressure gauge
- Intuitive operation of the Quadera[®] software
- World-class support and worldwide on-site service

The precise solution for mass spectrometry.

Overview of technologies

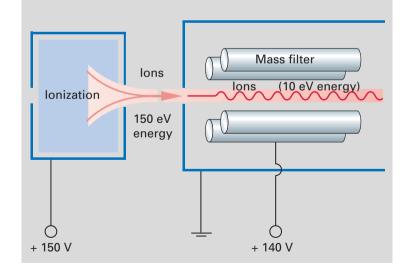
Biased ionization chamber

Biasing the ionization chamber results in an extremely low background signal. The electron-emitting filament is positively biased relative to ground. This design prevents desorption of gas particles from the chamber walls, and thus the generation of an undesired background signals by electron stimulated desorption.



Field-axis technology

One of the most important factors in the performance of a mass spectrometer is the transmission of the ions from the ion source into the mass filter. With the aid of field-axis technology, the ions are able to cross the peripheral fields of the separating system without any noteworthy interaction. This enables a high level of sensitivity (A/hPa) to be achieved without the need for pre and post filters.

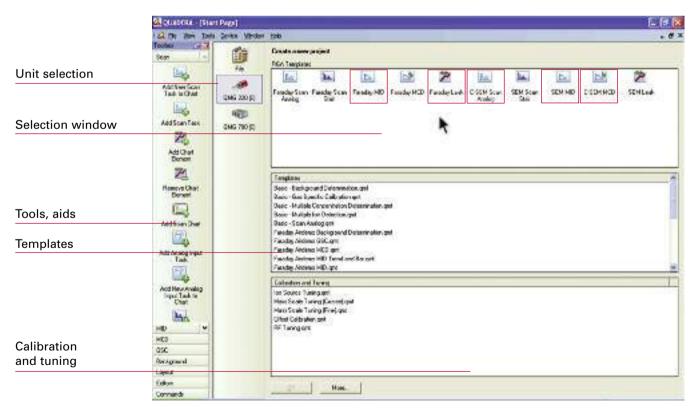


Quadera® – The PrismaPlus® software!



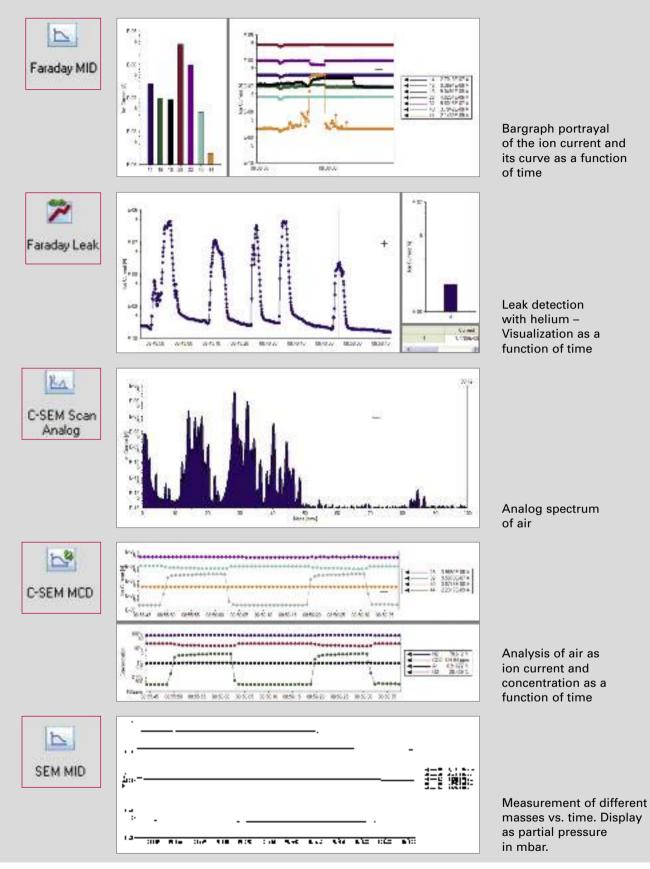
The Quadera[®] software is a further plus. With its modular design, it offers an easy-to-read, user-friendly platform for capturing and visualizing measured data and parameter records. Complete measurement procedures can be programmed.

- User-friendly, intuitive operation
- Customer-specific user interface
- Automated measurement routines via the integral VSTA script editor
- Measured data interchange through I/O module
- With stored library: Containing many common gases
- Simple definition of measurement recipes
- Mass spectrometer data can be linked with external signals



Clicking on the icons in the selection window launches the measurement task.

Measurement modes



PT M0a bcd efg

Detector version	а
Faraday ¹⁾	5
only for leak detection and high-vacuum residual gas analysis	•
C-SEM/Faraday	
C-SEM = Continuous Secondary Electron Multiplier for fast,	6
sensitive UHV residual gas analysis, analytical applications and leak detection	
Mass Range	b
1–100 amu	1
1–200 amu	2
1–300 amu	3
on sourche	С
Open ion source	1
for high-vacuum residual gas analysis; high sensitivity and good linearity	•
Gas-tight ion source	
for use in combination with gas inlet systems;	2
low gas consumption, high signal-to-noise ratio	
Crossbeam ion source ²⁾	
for direct gas beam inlet, without interaction with the walls of the ion source;	3
electron energy adjustable from 0 to 100 eV	
Grid ion source ²⁾	4
for UHV residual gas analysis; minimum outgassing and desorption rate	4
Open ion source for high-vacuum residual gas analysis; high sensitivity and good	5
linearity; electron energy adjustable from 0 to 100 eV - for soft ionization	5
Filament	d
Tungsten;	1
for UHV applications	•
Yttriated iridium;	2
low filament temperatures, high resistance to air inrushes	2
Bakeout temperature ³⁾	е
To 200 °C	1
To 300 °C	2
Connection ⁴⁾	f
0° (on one axis)	1
90° off axis	2
I/O module ⁵⁾ and VSTA software extension	g
Without option	0
With I/O module for control and signal interchange via	
analog and digital inputs/outputs	1
With VSTA software extension for programming program sequences	
and for exchanging commands and data with other programs	2
With I/O module and VSTA software extension	3
	-

¹⁾ With open ion source only
²⁾ Ion sources with tungsten filament only
³⁾ Electronics removed

⁴⁾ See dimensions page 11

⁵⁾ See page 10

The precise solution for mass spectrometry.

Technical data

PrismaPlus	QMG 220 F1	QMG 220 F2	QMG 220 F3	QMG 220 M1	QMG 220 M2	QMG 220 M3	
Detector		Faraday (F)			C-SEM/Faraday (M)		
Mass range	1–100 amu	1–200 amu	1–300 amu	1–100 amu	1–200 amu	1–300 amu	
Rod system, diameter/length	6 mm / 100 mm						
Min. detection limit, Faraday ¹⁾	1 ⋅ 10 ⁻¹² hPa	2 ⋅10 ⁻¹² hPa	4 ·10⁻¹² hPa	5 ⋅10 ⁻¹² hPa	1 ⋅ 10 ⁻¹¹ hPa	2 ⋅10 ^{⋅11} hPa	
Min. detection limit, C-SEM ¹⁾	-	-	-	1 ⋅10 ⁻¹⁴ hPa	< 2 · 10 ⁻¹⁴ hPa	< 4 ·10 ⁻¹⁴ hPa	
Ar sensitivity, Faraday ¹⁾	1 ⋅10 [⋅] ³ A/hPa	6 ·10⁴ A/hPa	3 ·10⁻⁴ A/hPa	5 ⋅10 ^{-₄} A/hPa	3 ·10⁻⁴ A/hPa	1.5 ·10 ^{-₄} A/hPa	
Ar sensitivity, C-SEM ¹⁾	-	-	-	200 A/hPa	200 A/hPa	100 A/hPa	
Max. operating pressure ²⁾ , Faraday operation			1 ⋅10 ^{-₄} hPa				
Max. operating pressure, C-SEM operation	-	-	-	1 ⋅10⁵ hPa	1 ⋅10 ^{.₅} hPa	1 ⋅10 ^{-₅} hPa	
Contribution to adjacent mass (40/41) ¹⁾	< 10 ppm	< 20 ppm	< 50 ppm	< 10 ppm	< 20 ppm	< 50 ppm	
Operating temperature, analyzer	150 °C						
Operating temperature, electronics				0–40 °C			
Bakeout temperature, analyzer ³⁾		200 °C / 300 °C					
Connection flange		DN 40 CF-F					
Resolution at 10 % peak height		0.5–2.5 amu					
Measurement speed, analog/bargraph scar	urement speed, analog/bargraph scan 20 ms – 60 s/amu						
Measurement speed, Stair				2 ms – 60 s/amu			
Measurement speed, MID				2 ms – 60 s/amu			
Number of measurement channels in MID		128					
Reproducibility of peak ratio				± 0.5 %			
Interface				Ethernet			
Input, digital				External protection			
Supply voltage				90–260 V AC, 50/60 Hz			
Weight ⁴⁾	2.4 kg	2.4 kg	2.4 kg	3.8 kg	3.8 kg	3.8 kg	

¹⁾ For open ion source
²⁾ With emission current reduced to 0.2 mA: 1 · 10³ hPa

³⁾ Defined by order number ⁴⁾ For variant with elektronic and analyzer on one axis (0°)

Accessories

I/O module 220	PT M28 699
SP 220 power supply (inclusive power cable)	PT 160 200
ActiveLine, PKR 360 ⁵⁾ , 1 · 10 ^{.9} – 1,000 hPa	PT T02 350 010
ActiveLine, PKR 361 ⁵⁾ , 1 · 10 ^{.9} – 1,000 hPa	PT T03 350 010
ActiveLine, PBR 260 ⁵⁾⁶⁾ , 5 · 10 ⁻¹⁰ – 1,000 hPa	PT R27 000
ActiveLine, TPR 280 ^{₅)} , 5 · 10 ⁻⁴ – 1,000 hPa	PT R26 950
Connection cable, ActiveLine gauge–QMG 220, 0.6 m ⁵⁾	PT 448 249-T
DigiLine, PPT 200⁵, 1 · 10⁴– 1,000 hPa	PT R38 130
DigiLine, HPT 200 ⁵⁾⁶⁾ , 5 · 10 ⁻¹⁰ – 1,000 hPa	PT R39 350
DigiLine, MPT 200 ⁵⁾ , 5 · 10 ^{.9} – 1,000 hPa	PT R40 350
Connection cable, DigiLine gauge–QMG 220, 3 m⁵	PT 348 223-T
Chambers and gas inlet systems	on request

⁵⁾ Can be used only in conjunction with I/O module ⁶⁾ Additional SP 220 power supply necessary

Scope of delivery



Applications

The PrismaPlus is the optimal solution for leak detection, residual gas analysis or complex, quantitative analyses:

- Metallurgy
- Vacuum furnaces
- Accelerators
- Sputter process analysis
- Semiconductor production

- Glass coating
- Research & development
- Vacuum process systems
- Lithography plants

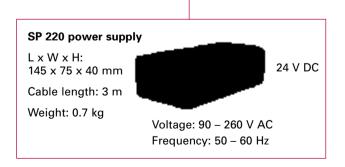


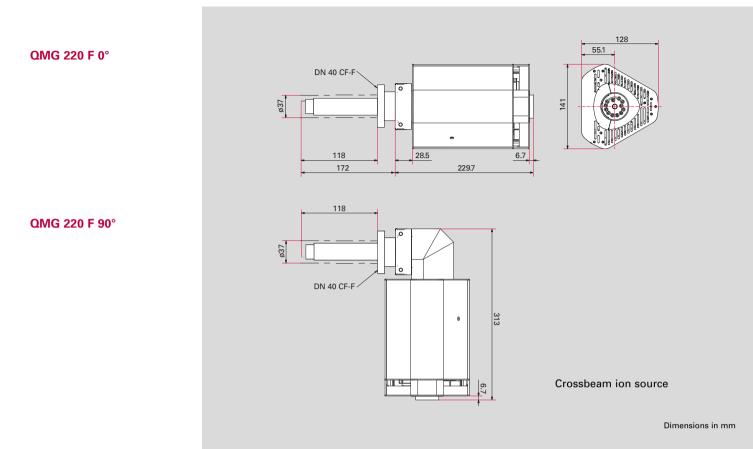
Differentially pumped PrismaPlus for processes between $1 \cdot 10^{-7}$ and 8 hPa (mbar)

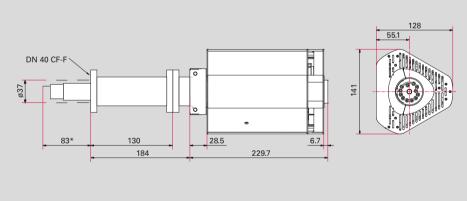


PrismaPlus on a residual gas analysis system

I/O module - Connection options **Digital outputs Digital inputs** Analog outputs **Analog inputs** 5 Number 4 5 16 Specification 0-10 V -10 - +10 V $V_{out} = 24 V$ $V_{in} = 24 V$ Resolution 12 bit 14 bit Application examples · Measured values, Reading in external Free assignment Starting or stopping of switchpoints e.g. ion currents values, e.g. pressure, measurement Ratios Valve actuation tasks by means of temperature, gas flow (concentrations) external signal Data transfer to higher-level systems 101 **Total pressure measurement Total pressure measurement** with ActiveLine with DigiLine® Ethernet

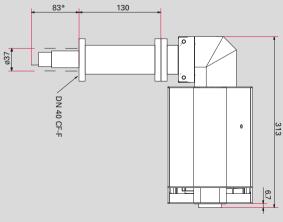


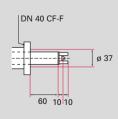






QMG 220 M 0°





Crossbeam ion source

* Gas-tight ion source = 90.6 Grid ion source = 92

Dimensions in mm

VACUUM SOLUTIONS FROM A SINGLE SOURCE

Pfeiffer Vacuum stands for innovative and custom vacuum solutions worldwide, technological perfection, competent advice and reliable service.

COMPLETE RANGE OF PRODUCTS

From a single component to complex systems: We are the only supplier of vacuum technology that provides a complete product portfolio.

COMPETENCE IN THEORY AND PRACTICE

Benefit from our know-how and our portfolio of training opportunities! We support you with your plant layout and provide first-class on-site service worldwide.

Are you looking for a perfect vacuum solution? Please contact us:

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